CLAIMS

1. An abatement apparatus (10) for abatement of an effluent stream from a semiconductor processing tool, comprising:

combustion chamber (120) formed by

a foraminous sleeve (90; 90a) defining an upstream portion of said combustion chamber for treating said effluent stream, said upstream portion of said combustion chamber having an inlet for receiving said effluent stream and

a wetted sleeve (1020) fluidly coupled with foraminous sleeve, said wetted sleeve defining a downstream portion of said combustion chamber, wherein said foraminous sleeve is configured to provide a foraminous axial surface facing downstream towards said downstream portion of said combustion chamber; and characterised in that said foraminous sleeve is at least partially housed within a radially outer sleeve (1050) extending at least partially along an axial length of said foraminous sleeve to define a plenum for delivery of combustion materials to be conveyed through said foraminous sleeve for combustion thereon and said outer sleeve fails to extend to said foraminous axial surface to expose at least a radially outer edge (1060) of said foraminous axial surface to support combustion thereon.

2. The abatement apparatus of claim 1, wherein said foraminous axial surface is orthogonal to said wetted sleeve.

3. The abatement apparatus of claim 1 or 2, wherein said foraminous sleeve has at least one inward-facing surface defining said upstream portion (120a) of said combustion chamber and said foraminous axial surface at least partially defines an upstream portion outlet.

4. The abatement apparatus of claim 3, wherein at least a portion of said foraminous axial surface is orthogonal to said inward-facing surface (1000).

5. The abatement apparatus of claim 3 or 4, wherein said inward-facing surface (1000) is orientated to be generally parallel to a major direction of flow of said effluent stream in said combustion chamber and at least a portion of said foraminous axial surface is orientated to be generally orthogonal to said major direction of flow of said effluent stream.

6. The abatement apparatus of any preceding claim, wherein said foraminous axial surface is at least one of planar and curved.

7. The abatement apparatus of any preceding claim, wherein said combustion chamber is tubular.

8. The abatement apparatus of any preceding claim, wherein said combustion chamber is one of cylindrical and cuboid and said foraminous axial surface is one of annular and an annular quadrilateral.

10. The abatement apparatus of any preceding claim, wherein said wetted sleeve (1020) is housed within a wetted sleeve housing and said foraminous axial surface is positioned at least flush with an upstream surface of said wetted sleeve housing.

11. The abatement apparatus of claim 10, wherein said upstream surface has a deflecting lip depending from said upstream surface and said foraminous axial surface is positioned at least flush with an edge of said deflecting lip.

12. The abatement apparatus of claims 10 or 11, wherein said foraminous sleeve is positioned to extend within said wetted sleeve to position said foraminous axial surface below said upstream surface.

13. The abatement apparatus of any preceding claim, comprising a purge conduit configured to deliver a purge gas to an exposed radial outer surface of said foraminous sleeve extending within said wetted sleeve.

14. The abatement apparatus of any preceding claim, comprising a plurality of upstands configured to extend to at least said foraminous axial surface.